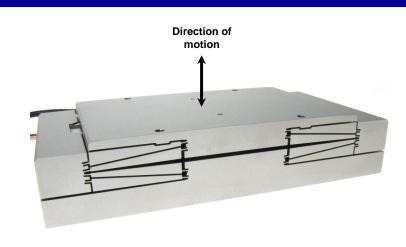
ZSA-1000C 1mm Nanopositioning Piezoelectric Z-Axis Stage



Description

DSM's nanopositioning piezoelectric ZSA-1000C stage features flexure-guided motion over a 1mm vertical travel range for scanning, metrology, and inspection processes. The stage's stable and stiff kinematic design promotes parallelism in the output motion with minimal roll and tilt as well as dynamic responsiveness for excellent position stability and control. In semiconductor industry applications, the stage has been implemented in closed-loop control using DSM's SA series servo amplifier and a high-resolution capacitive probe to provide 20 nm position stability and very stable velocity profiles over specified scan regions.



Specifications

Motion Direction: Contracting
 Open-Loop Travel: 1050 μm ± 10%
 Closed-Loop Travel: 1000 μm ± 10%

Closed-Loop Resolution: 20 nanometers typical

• Stiffness: 0.4 N/ μ m \pm 10%

Blocking Force: 400 N

Linearity: 0.12% typical
 Angular Error (Θx, Θy): <100 μrad typical
 Unloaded Resonant Freq: 200 Hz ± 10%

• Resonant Freq @100g: 150 Hz ± 10%

Push/pull force capacity: 75/150 N Max

Load capacity: 75 N MaxLateral Force: 10 N Max

Electrical Capacitance: $30 \mu F \pm 10\%$

Operating Voltage: -30 to +150 V

• Operating Temp Range: 5 to 50 °C

Dimensions: 62.5 x 125 x 25.1 mm

Mass: 1 kg ± 10%
Material: Stainless steel
Cable Length: 1.5 meters
Mounting Interface: 4x M3x0.5
Output interface: 4x M3x0.5

Application Fields

- Precision Manufacturing
- Microscopy
- Laser systems
- Material Science
- Optics/Photonics
- Electronics Manufacturing
- Science & Research institutions
- Test & Inspection Systems

System Configuration

Integrated Sensor: Capacitive
 Servo Amplifier: DSM SA-500

Amplifier bandwidth: >4 kHz

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